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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Docket No: Q60716

Hiromoto OHNO, et al.

Group Art Unit: 3749 Appln. No.: 10/088,306

Confirmation No.: 2926 Examiner: Not Yet Assigned

Filed: March 18, 2002

CLEANING GAS FOR SEMICONDUCTOR PRODUCTION EQUIPMENT For:

REQUEST FOR CORRECTED OFFICIAL FILING RECEIPT RECEIVED

Commissioner for Patents Office of Initial Patent Examination Customer Service Center Washington, D.C. 20231

TECHNOLOGY CENTER R3700

Sir:

We enclose a copy of the Official Filing Receipt for the above-identified application and request the following correction(s):

Applicant(s)

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Verification for the requested correction(s) is indicated on the original Declaration and Power of Attorney filed March 18, 2002.

Respectfully submitted,

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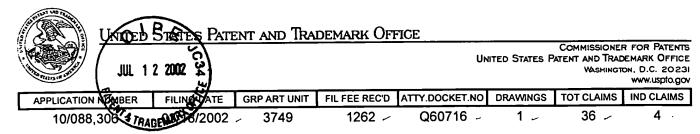
Date: July 12, 2002

Abraham J. Rosner Registration No. 33,276

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CONFIRMATION NO. 2926

FILING RECEIPT *QC000000008249357*

23373 SUGHRUE MION, PLLC 2100 PENNSYLVANIA AVENUE, N.W. WASHINGTON, DC 20037

Date Mailed: 06/11/2002

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Applicant(s)

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Domestic Priority data as claimed by applicant

THIS APPLICATION IS A 371 OF PCT/JP01/06164 07/17/2001 * WHICH CLAIMS BENEFIT OF 60/230,811 09/07/2000 * AND CLAIMS BENEFIT OF 60/261,265 01/16/2001 * (*)Data provided by applicant is not consistent with PTO records.

Foreign Applications

JAPAN 2000-217610 07/18/2000 JAPAN 2000-397269 12/27/2000 JAPAN 2001-189388 06/22/2001 -

Projected Publication Date: To Be Determined - pending completion of Security Review

Non-Publication Request: No

Early Publication Request: No

Title

Cleaning gas for semiconductor production equipment

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